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SIL8000 Wafer Loader

Automatic wafer loader for microscopes



SIL8000 Wafer Loader

The new SIL8000 wafer Loader represents the most simple system to automatically load wafers on a microscope. It is a compact unit, featured by a structure which makes possible to load wafers on almost any microscope without the need of complex interfaces and without having to change the microscope stage. There are two versions available, one for wide space microscopes and one for old microscopes featuring wafer rotation to reach any type of stage.

The system is featured by a powerful computer control with a user friendly interface and a touch screen.

Its software has recipe management to easily switch between different wafer size and thickness, and features different wafer selection methods to cover any inspection need. A simple macro inspection function can as well be done and can be equipped with optional LED illuminator.



Specifications	
Wafer size	150 - 200 mm - software change (other sizes on request)
Wafer thickness	250 – 760 µm
Clean room compatibility	Class 10 clean room compatible (parts in contact with wafer)
Control	Computer control with touch screen operator interface
Type of inspection	Micro inspection - Front macro inspection
Inspection mode	Sequential, sampling or statistical access
Cassette mapping	Laser sensor with thin wafer (>250 µ) detection capability
Compatible microscopes	LEICA DM8000 - other microelectronics microscopes
Footprint	W 500 x D 550 x H 350
Facilities	AC 220 - 240 V - 3,5 A 50 /60 Hz Vacuum - 60 to -90 KPa - 10 l/min Compressed air 6 bar - 1 nl/min

(Specifications are subject to change without any obligation on the part of manufacturer)

